

**Performance Evaluation of a  
Parallel Cantilever Biaxial Micropositioning Stage**

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2000 Annual Meeting  
Scottsdale, Arizona

Intelligent Systems and Precision Engineering Divisions  
Manufacturing Engineering Laboratory  
National Institute of Standards and Technology

# List of Other Participating NIST Staff

**PED Division:**

Dr. Lowell Howard

**MMD Division:**

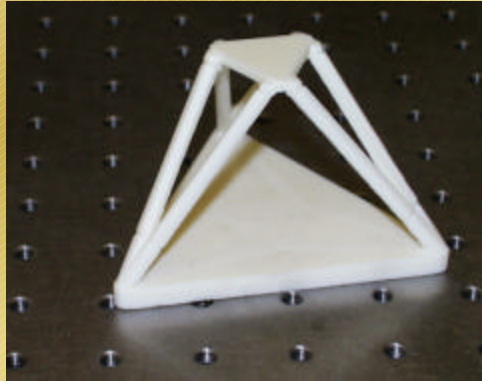
Dr. E. Clayton Teague

**ISD Division:**

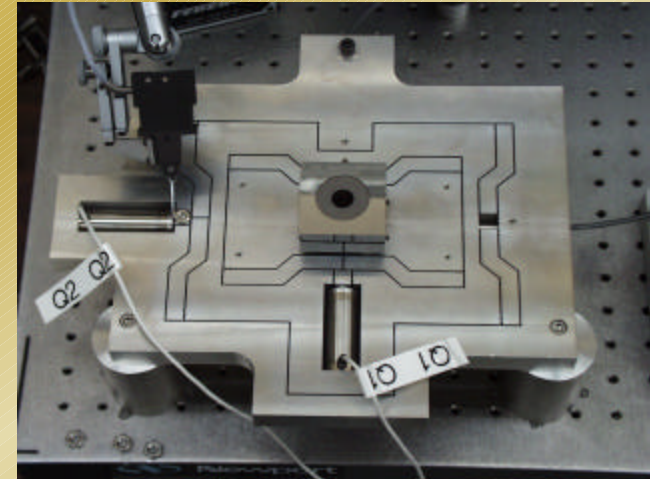
Mr. Robert Bunch

Mr. James Gilsinn

Mr. Brian Weiss



## Outline



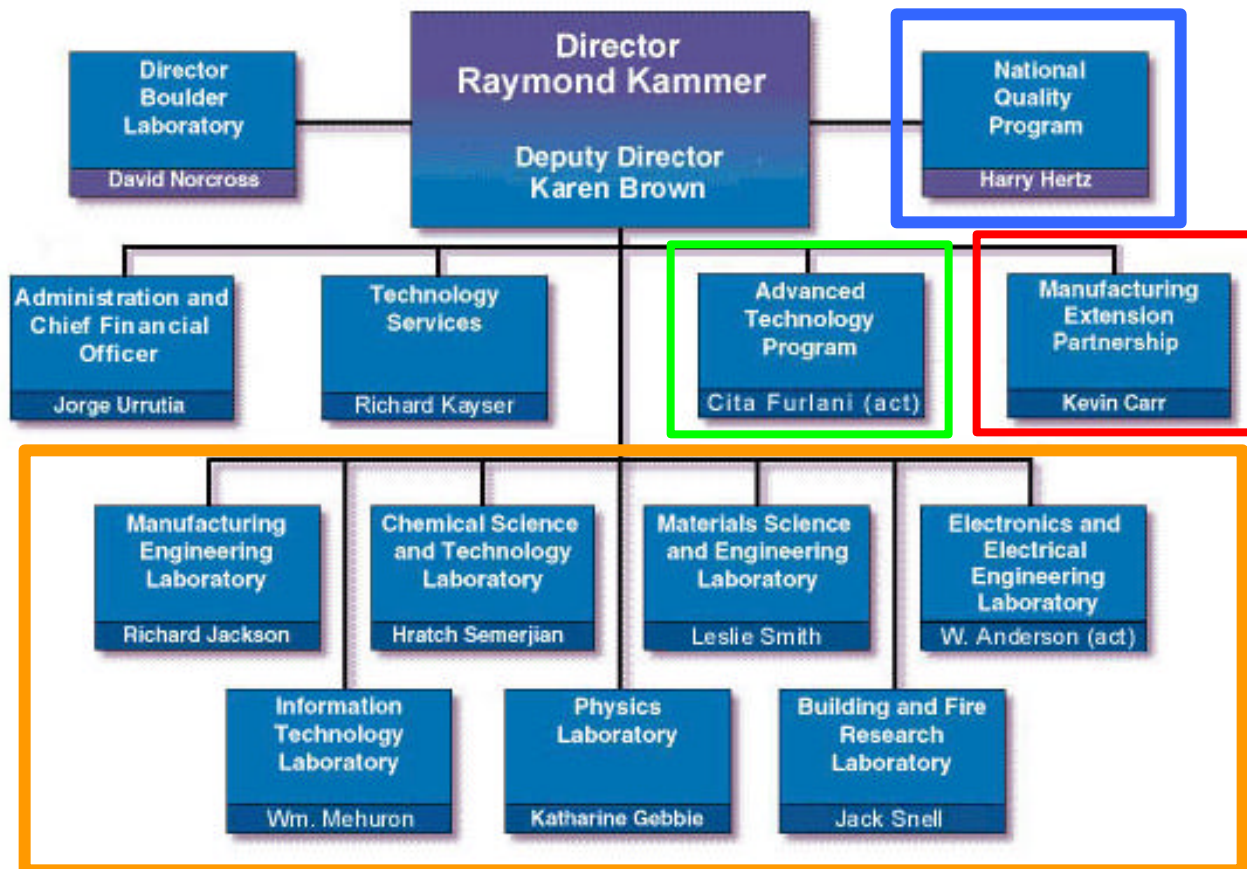
- Project Background, Research Objectives
- System Overview
- Planar Micro-Positioners: Models, Performance Testing, and Calibration
- Future Work, 3D Space Micro-Positioners
- Summary

Project Background  
and  
Research Objectives

# Manufacturing Engineering Laboratory

## National Institute of Standards and Technology

### NIST Organizational Chart



Last Updated Monday, 14-Feb-00 14:23:51

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# *Manufacturing Engineering Laboratory*

## Precision Optoelectronics Assembly Consortium



### Adept Facility, September '99, Final POAC Meeting

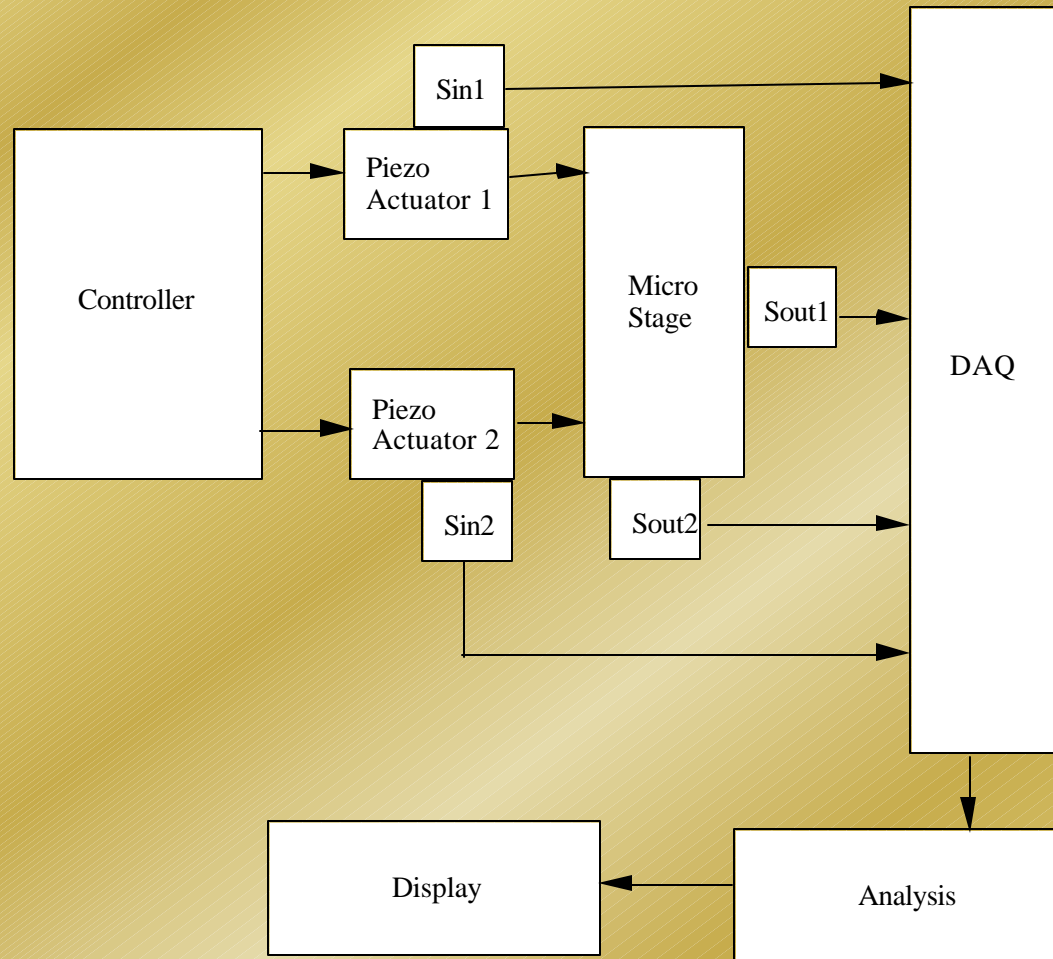
NCMS, Adept Technology, Inc. , Boeing Co. , Corning, Inc. , Focused Research, Inc. , SRI International , NJIT, NIST/MEL, NIST ATP present for final meeting.

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## **Objective: Performance Testing and Calibration of Micro-Positioners for Meso-Manufacturing**

- Develop performance tests, including quick and simple tests, in order to improve the reliability of micro-positioners.
- Develop calibration procedures in order to improve the accuracy of operation of micro-positioners.
- Measure the performance of various micro-positioner configurations, couplings and calibration fixtures.

## Block Diagram of Testing Setup

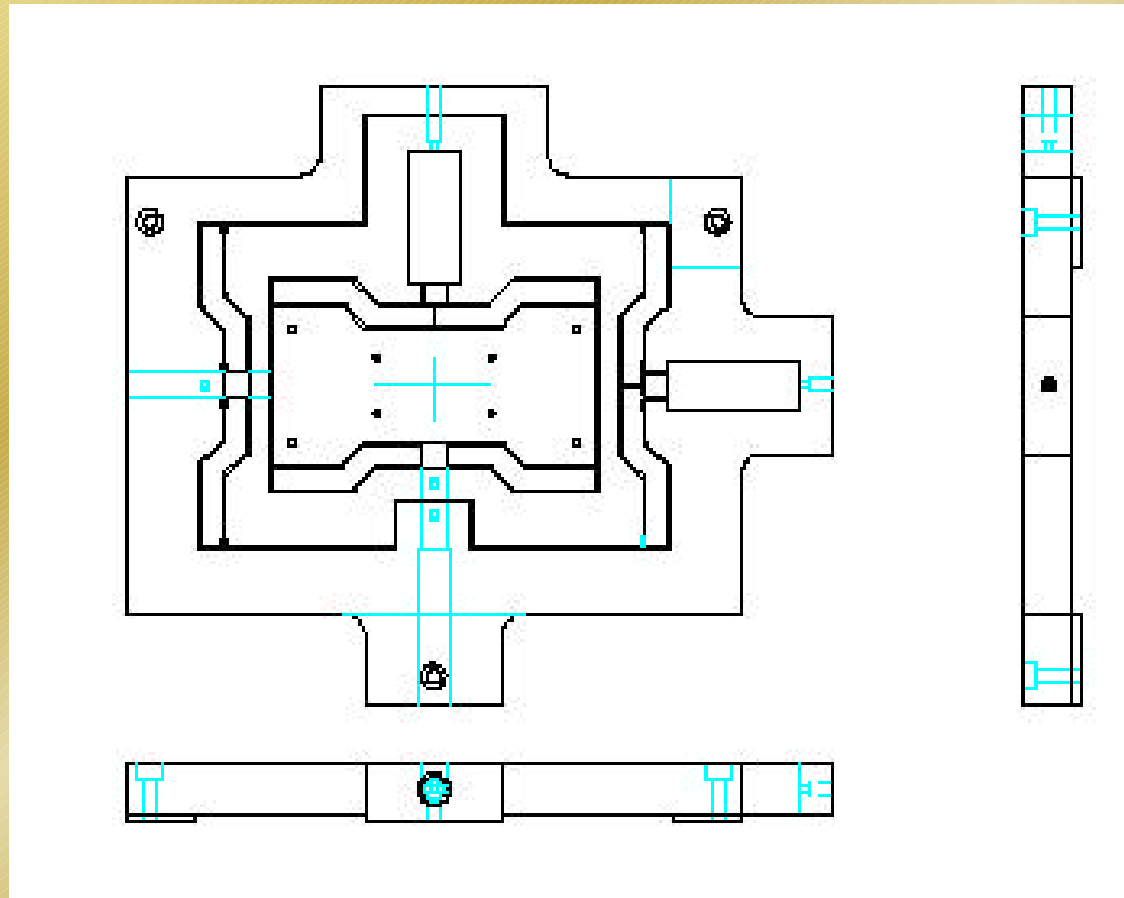


### Design Objectives

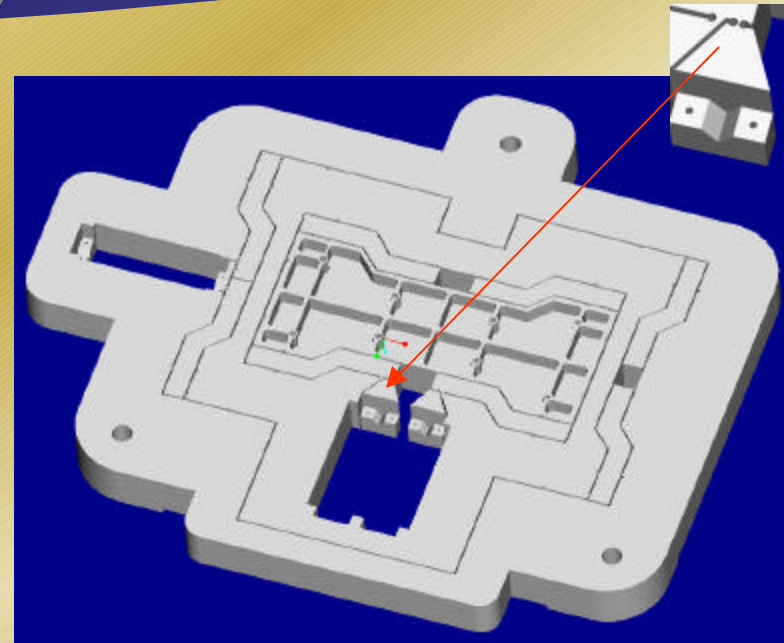
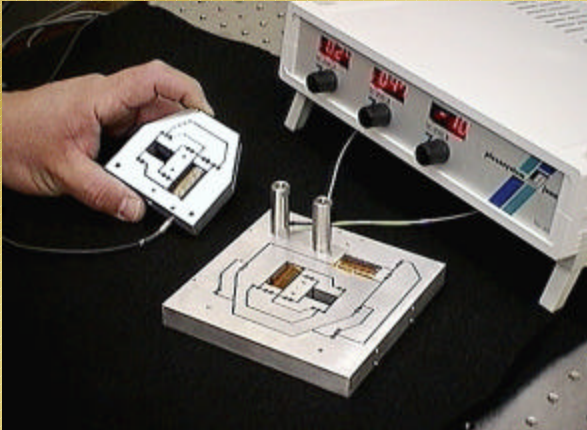
1. **Improve linearity of the stage structure.**
2. **Minimize off axis motion (cross talk).**
3. **Increase the range of motion of the stage.**
4. **Keep the resonant frequency above a desired level.**



# System Overview



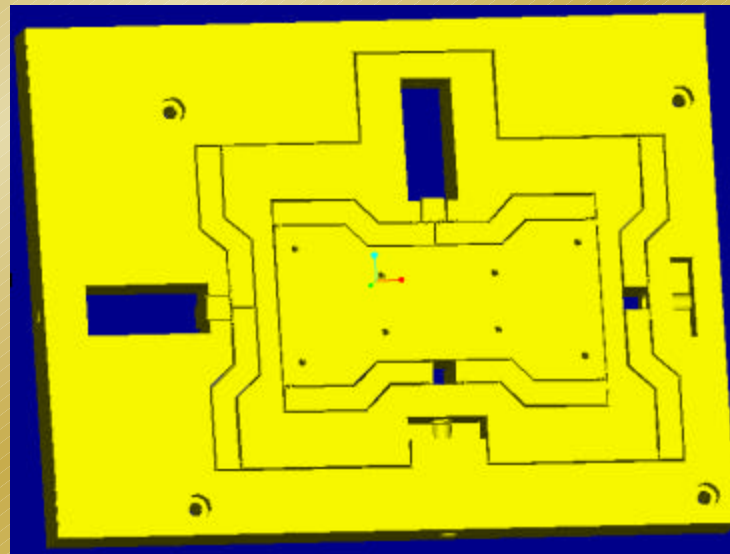
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Wye Creek Instruments

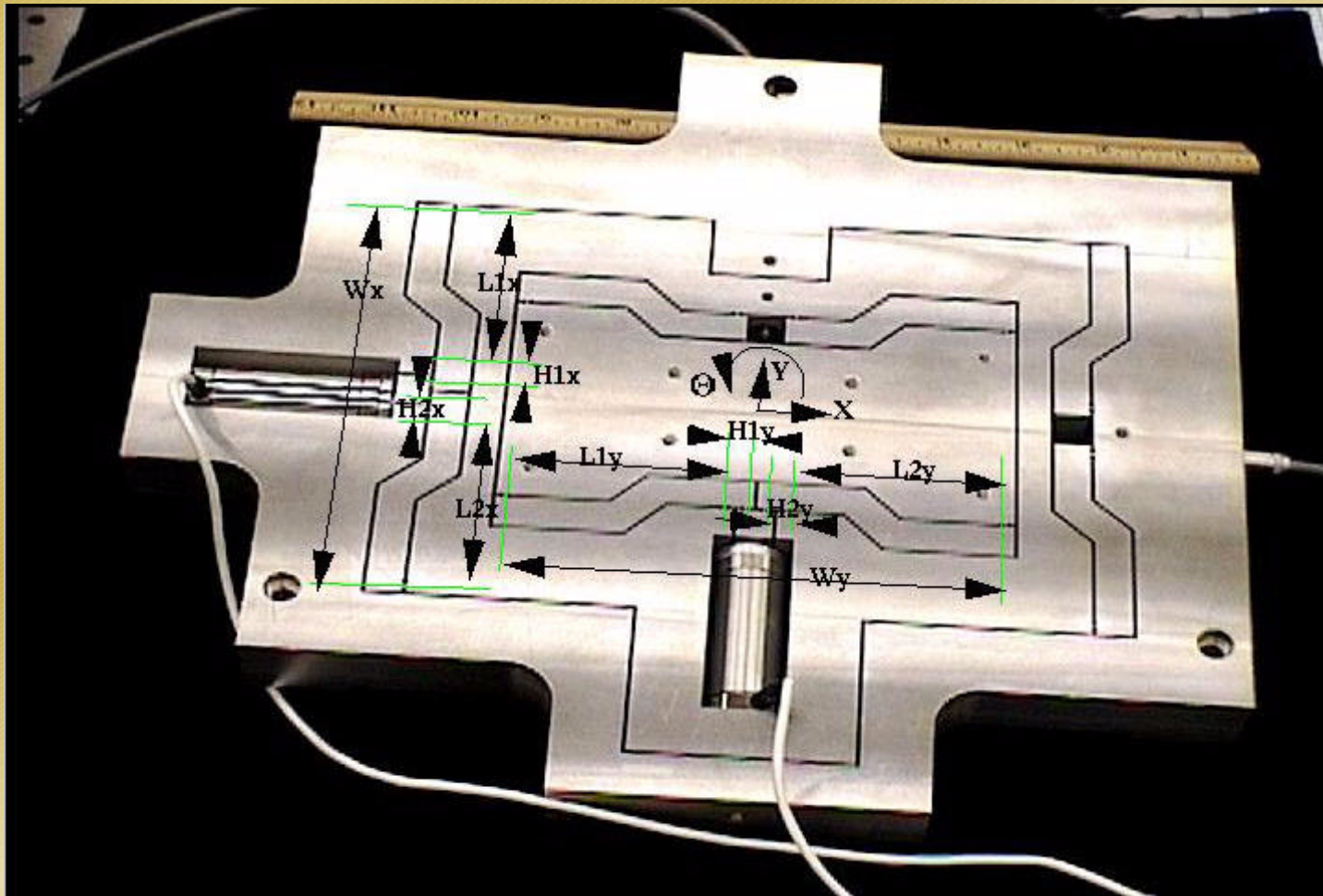
Fred Scire, NIST

Patented "PiezoFlex"

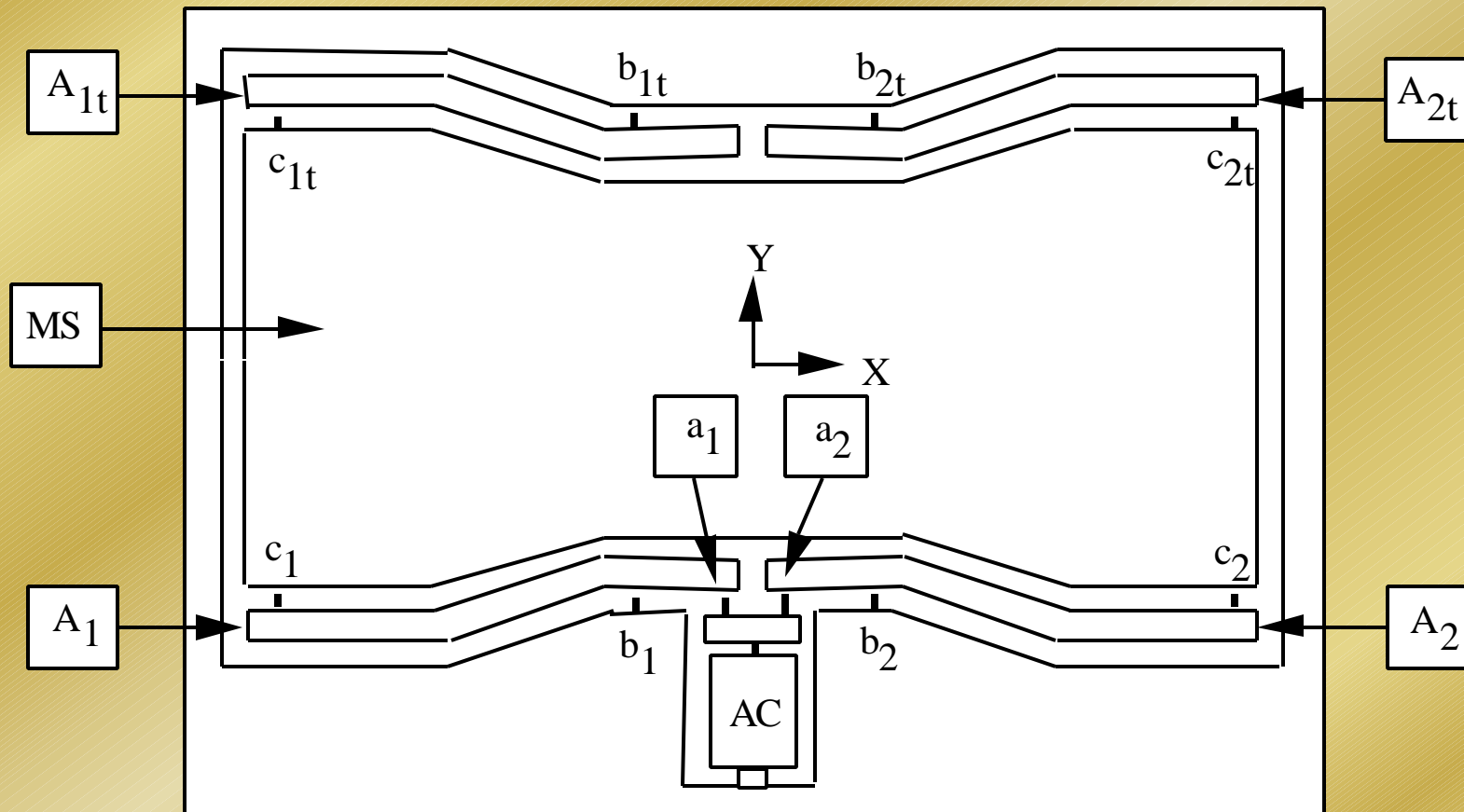


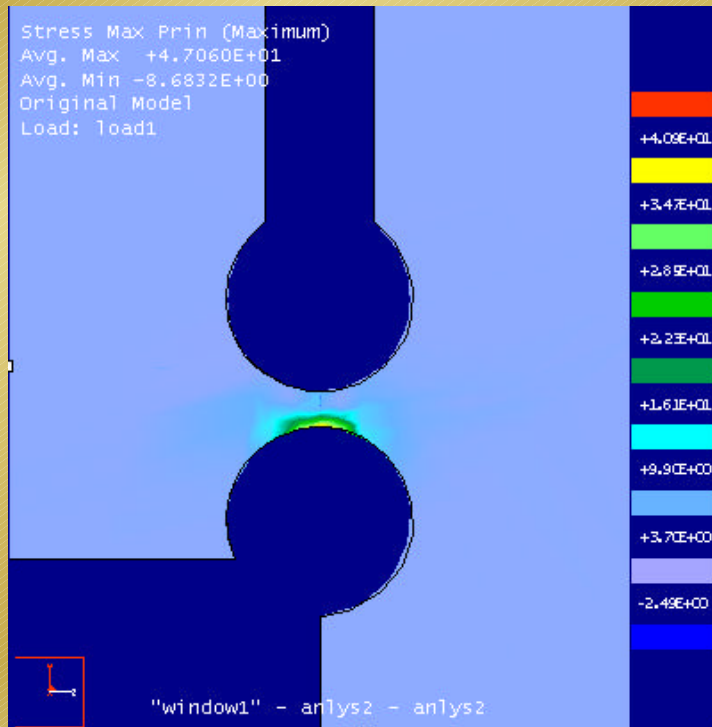
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# Parallel Cantilever Geometry



# Schematic of Y axis





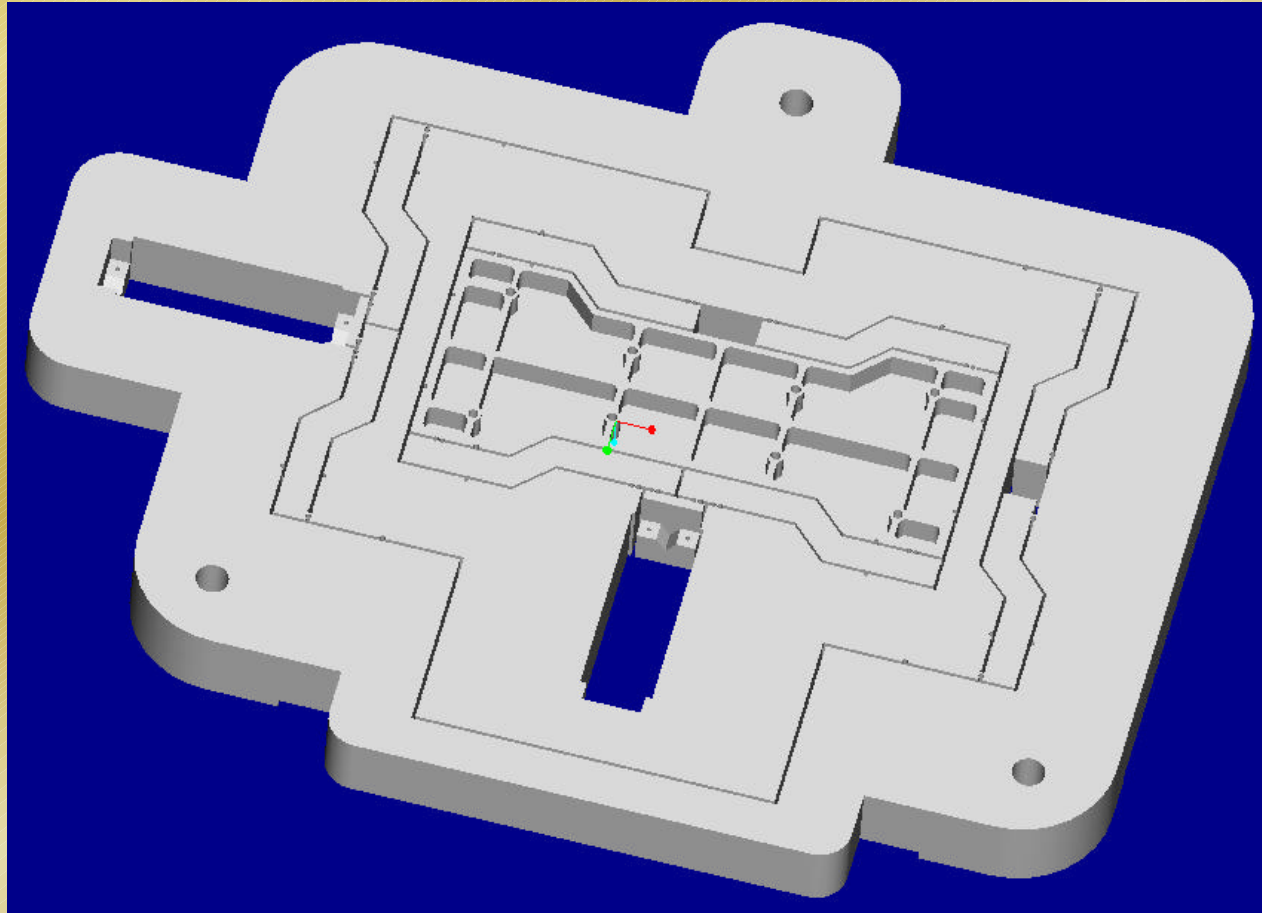
## Flexure Analysis

1.7mm holes

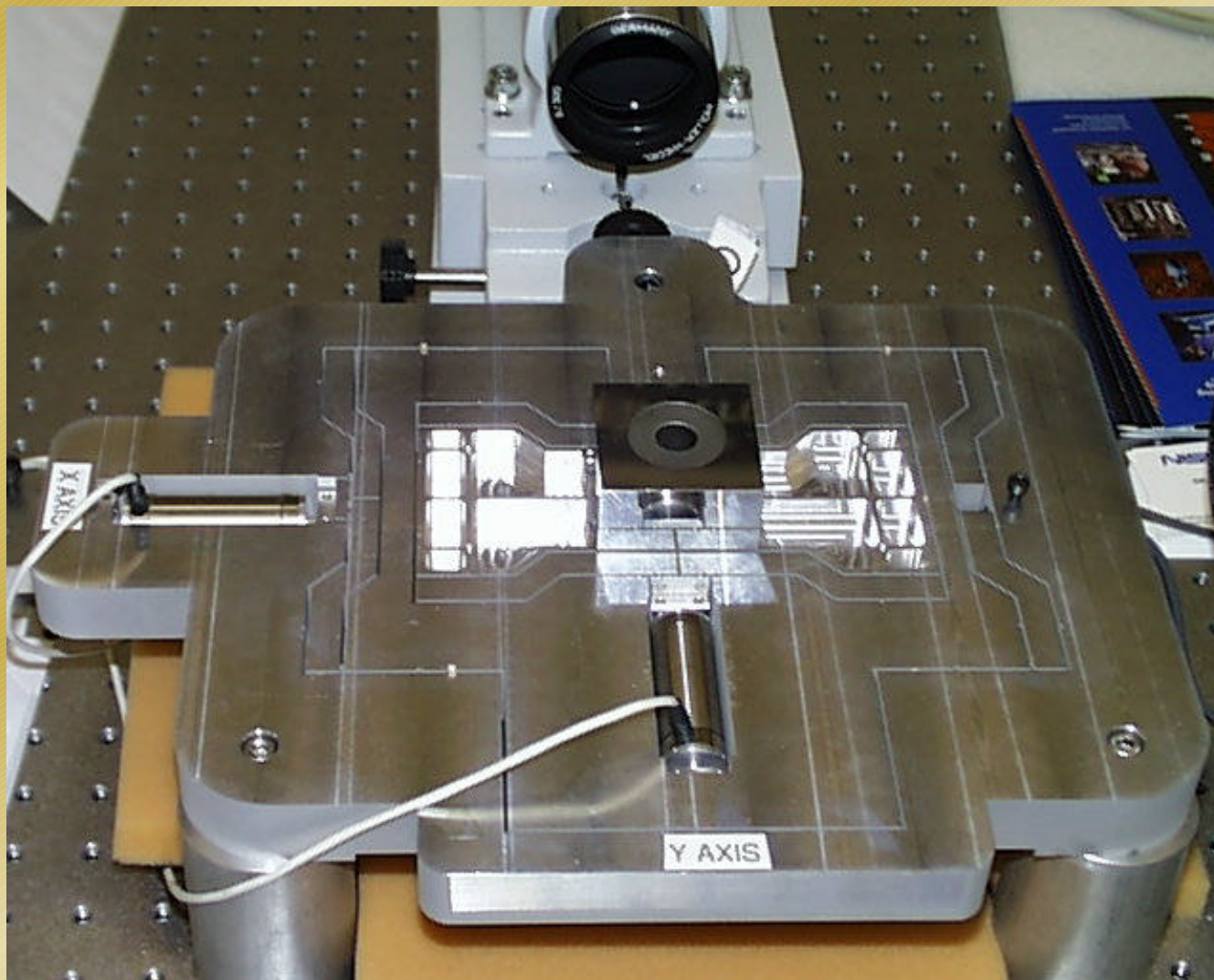
.3 mm web  
thickness

The flexure only experiences a stress of about **47 MPa** illustrated by the fringe pattern for a deflection of 15 micrometers. For **6061-T6 Aluminum**, the maximum yield strength is **255 MPa**. Since we are below this value, the flexure should not yield. BeCu and other materials maybe used to improve performance.

# X-Y Microstage Revision

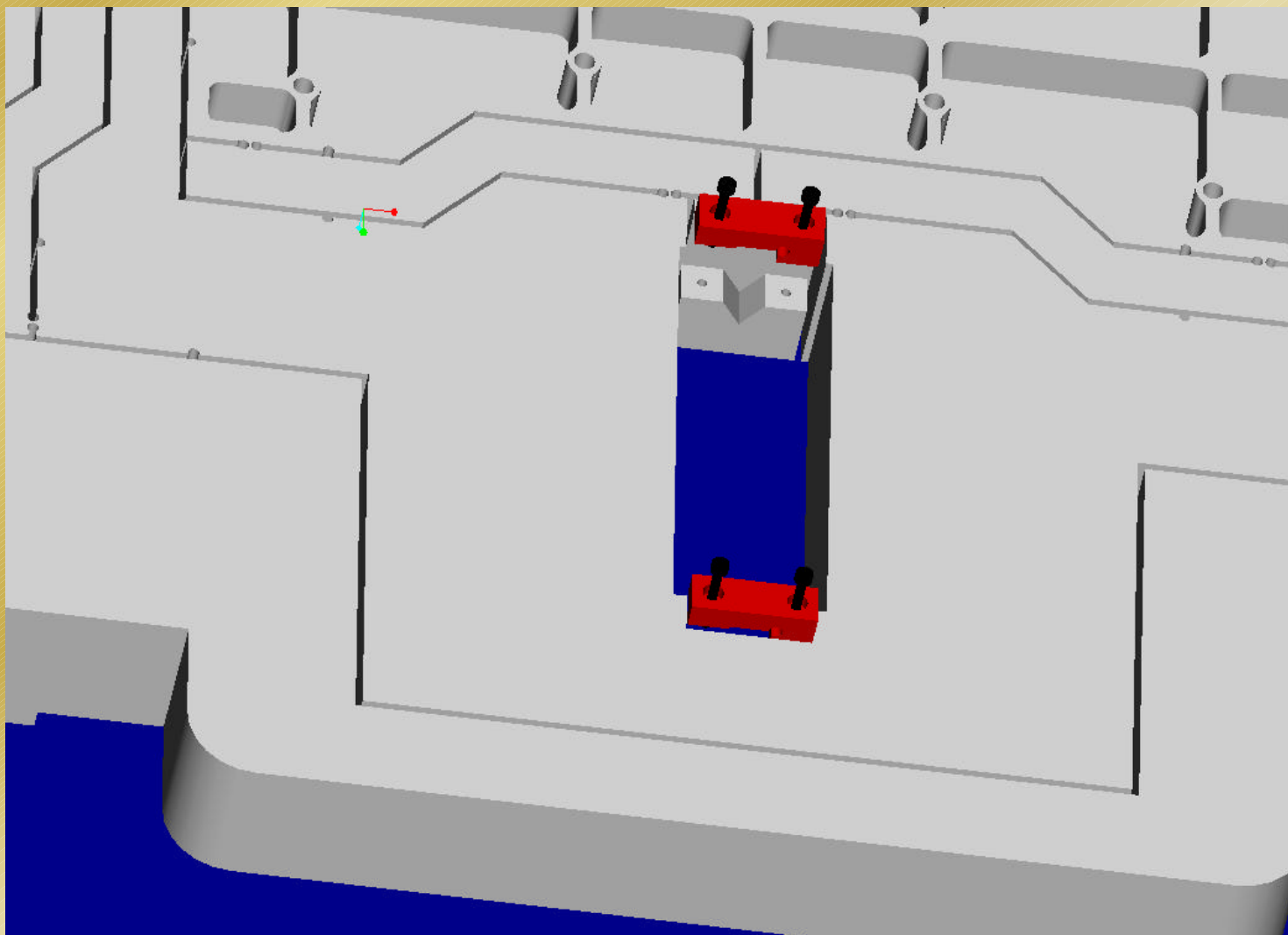


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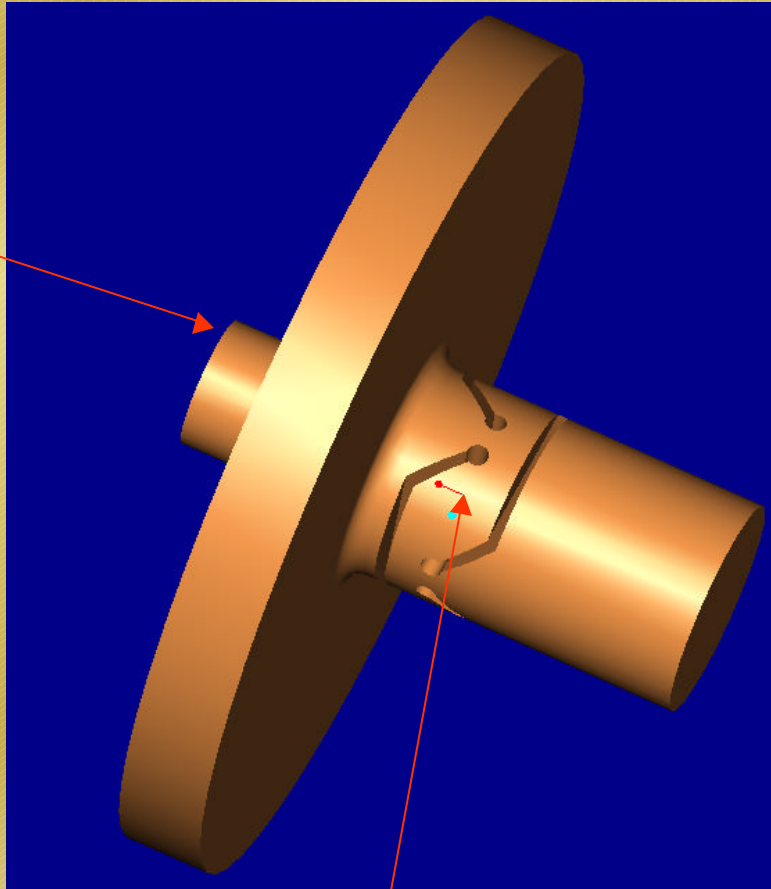
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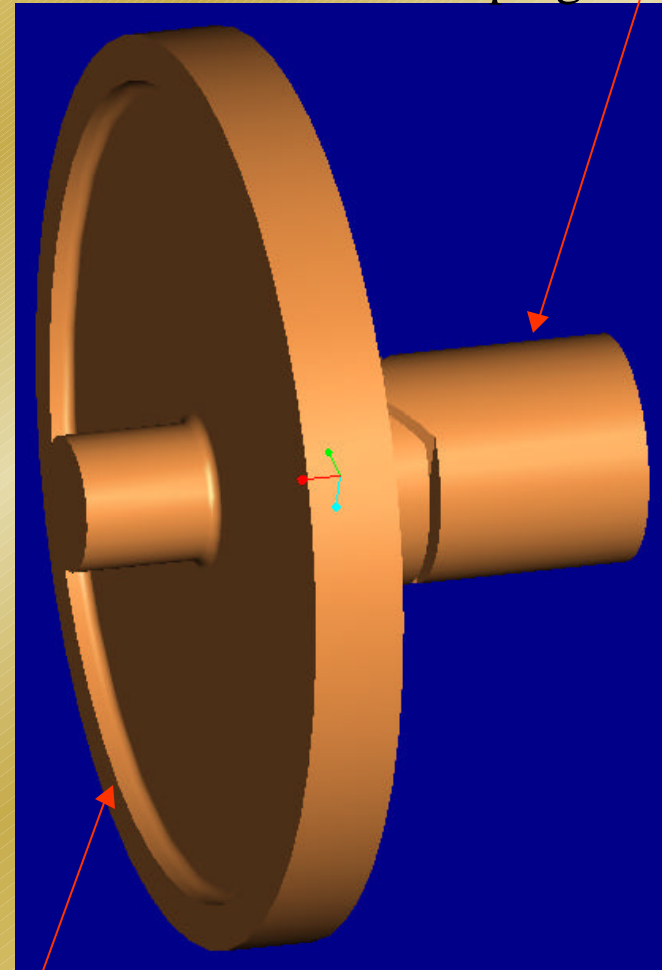


Threaded



Shortened Flexure  
Universal Joint

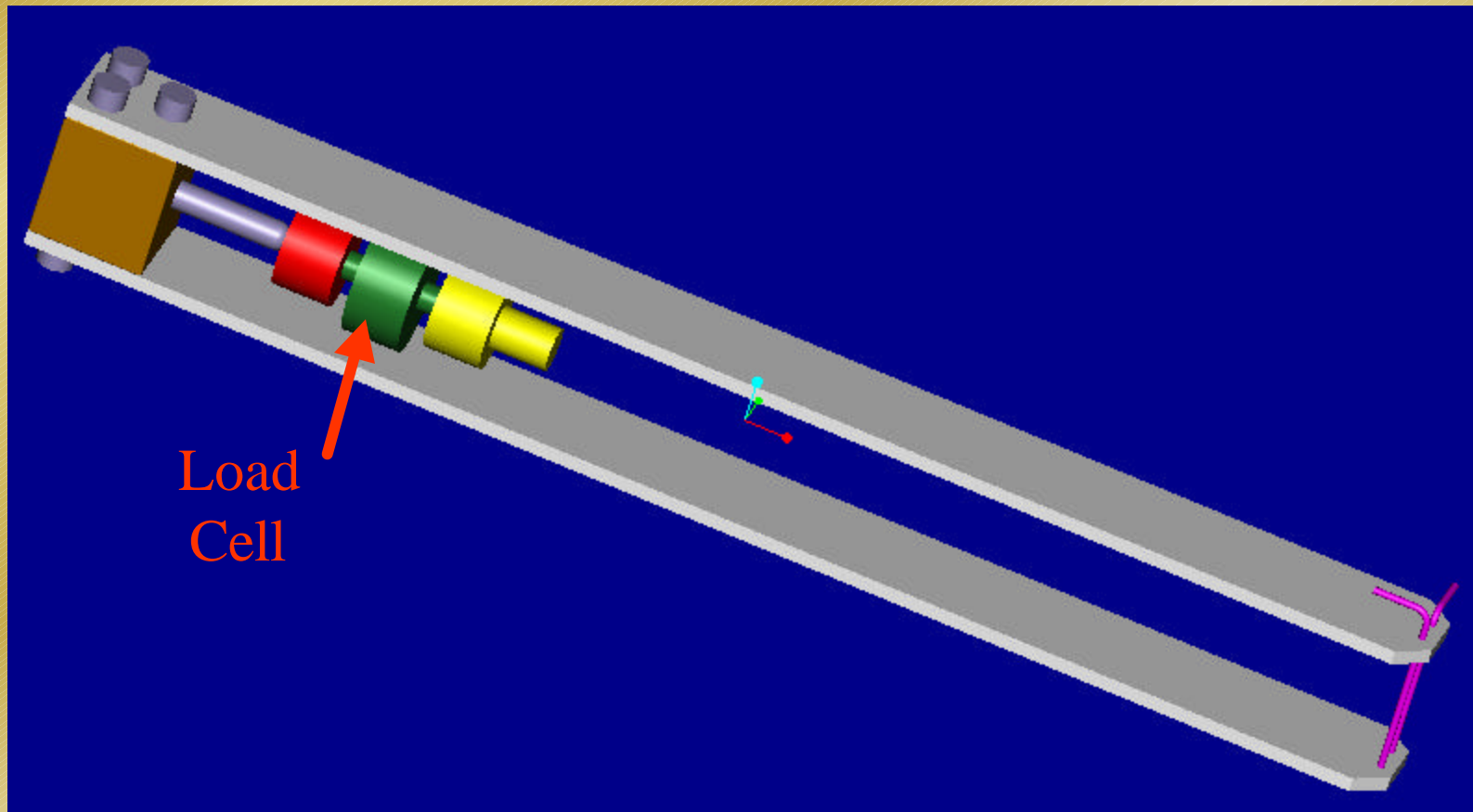
Clamping Surface



Raised Edge - reduces coupling  
loss of threads

Optimized Coupler for PZTs on X-Y Stage

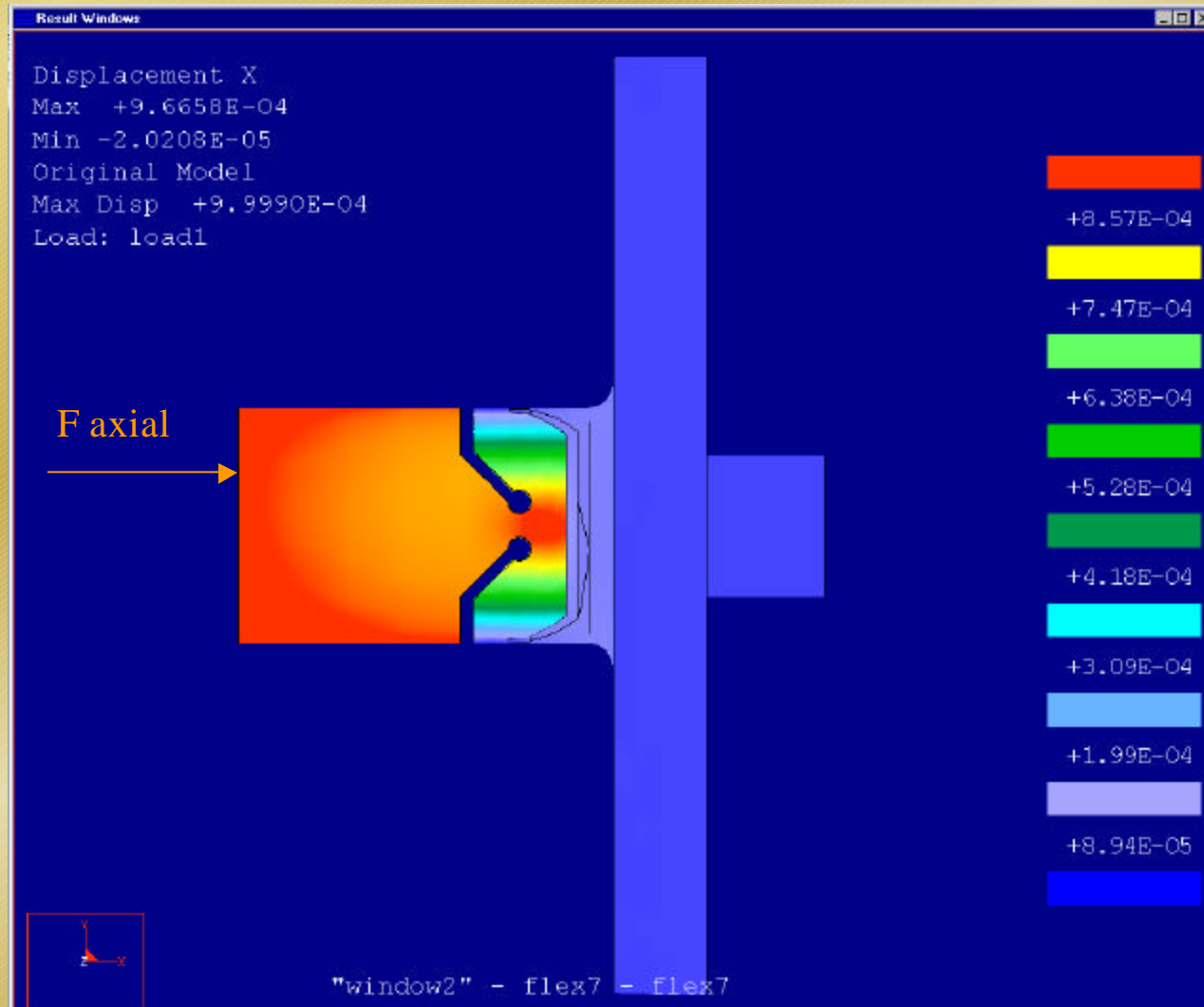
## Pre-Load Mechanism for PZT Assembly



Used for establishing proper Preload on PZT's and  
determining stage stiffness

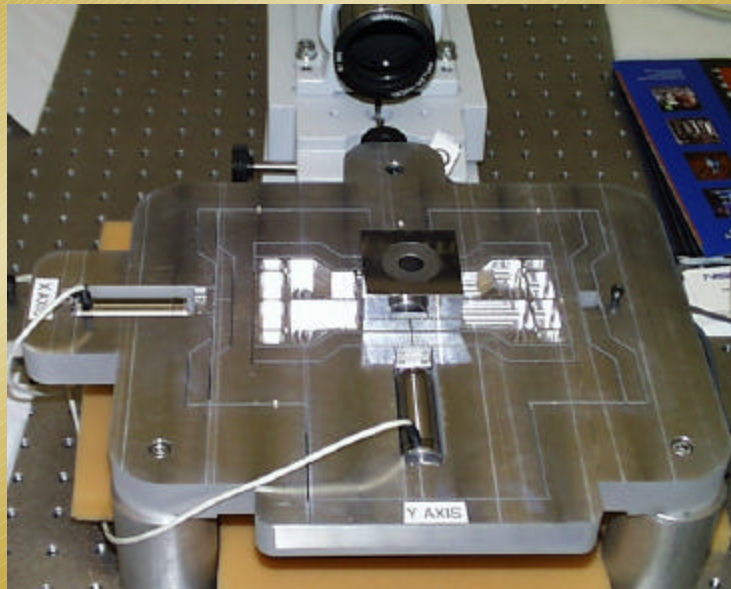
## Axial Flexure Displacement

$F_{axial} \sim 22.24N$   
Displacement  
 $\sim 0.00097$   
or 1 micrometer



# Coupler Re-design Conclusion

- Old Stage - glued, fixed PZT stacks - .6 arcsec yaw errors
- Old Stage - coupler installed on one side - .3-.4 arcsec yaw errors
- New Stage - couplers on both sides of PZT - .04-.12 arcsec yaw errors

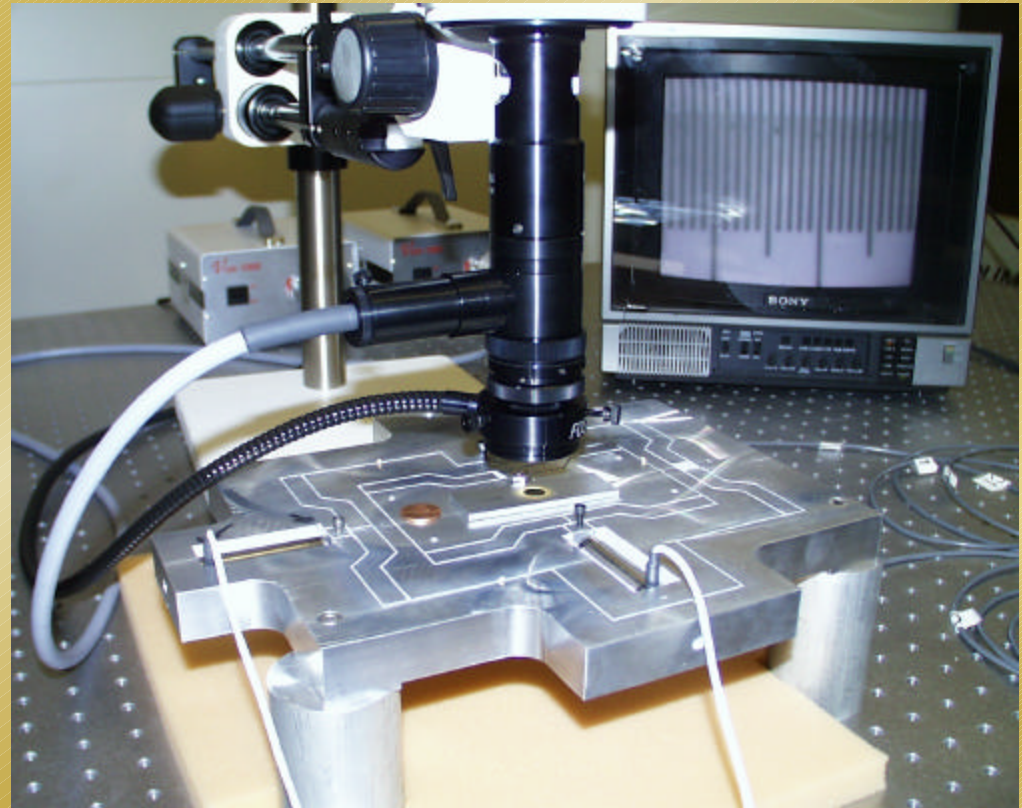


# Planar Micro-Positioners: Models, Performance Testing, and Calibration



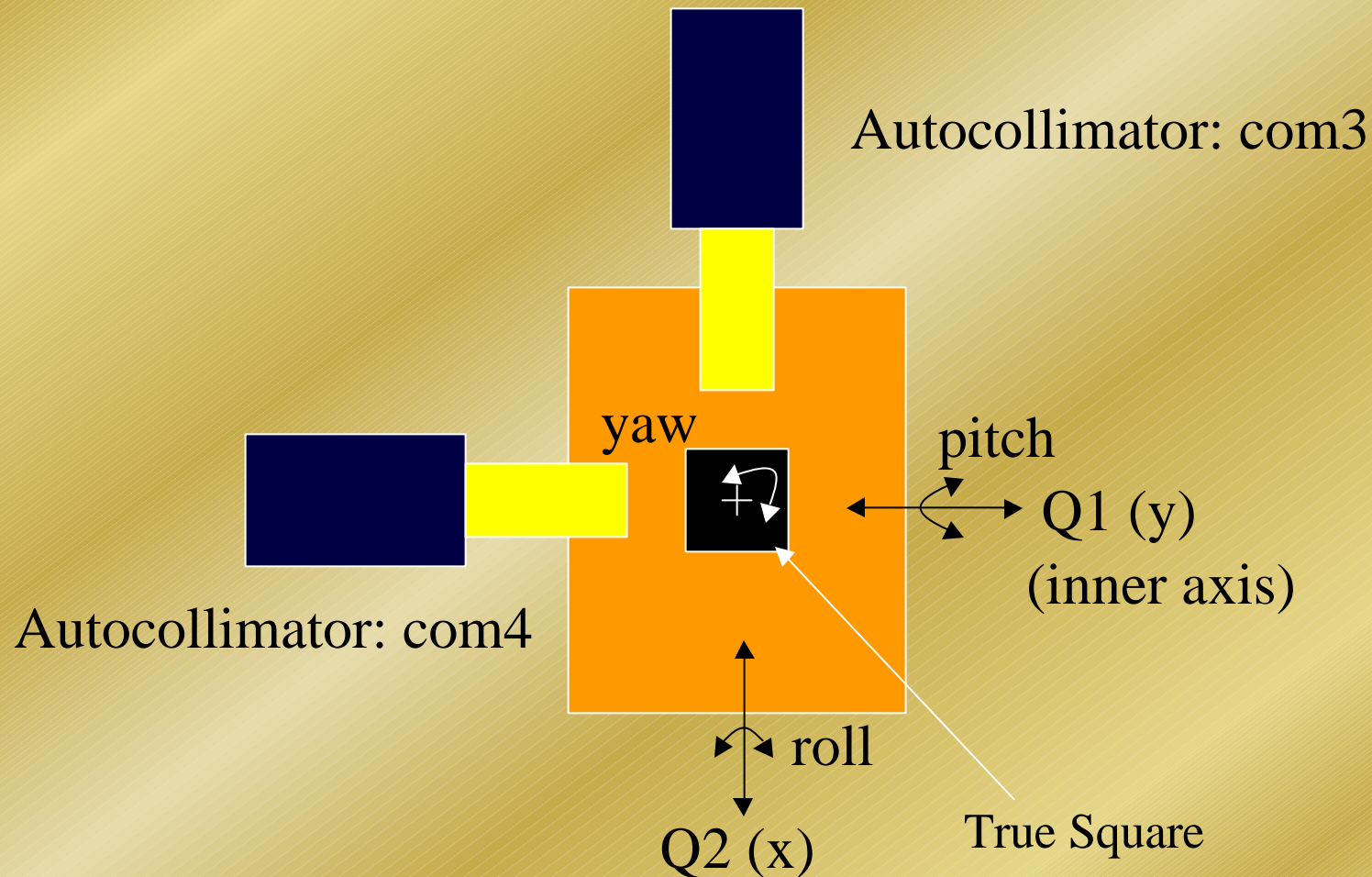
# Stage Motion Performance Tests

- X-Y Axes Cross Talk
- Angular Error Measurements
- Stage Linearity
- Mechanical Coupling
- Transmission Ratio
- Stage Calibration



(for example: mathematical models - identify parameters of kinematic model - leads to better control performance.)

# Measurement Setup



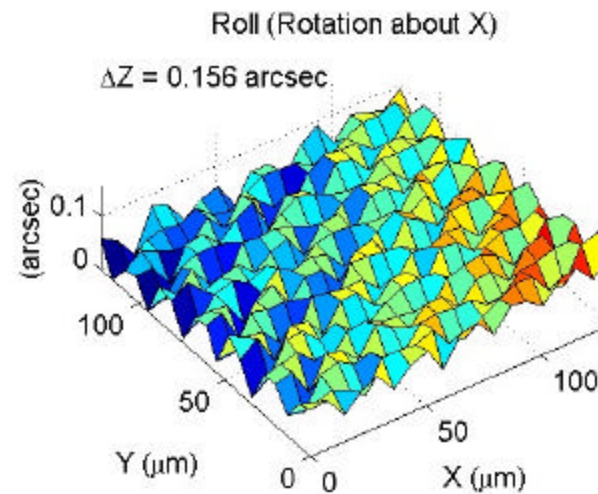
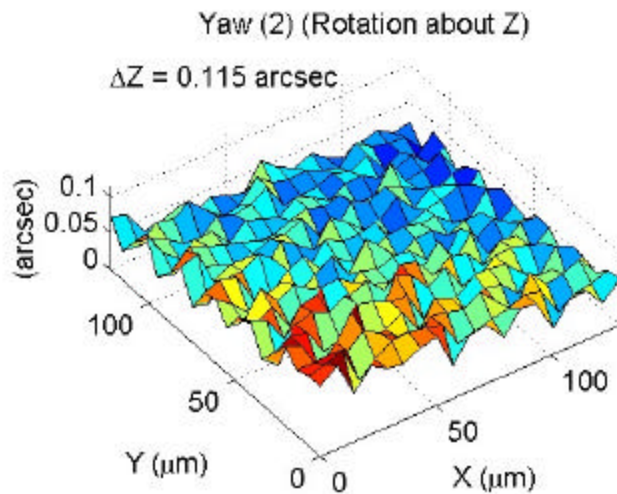
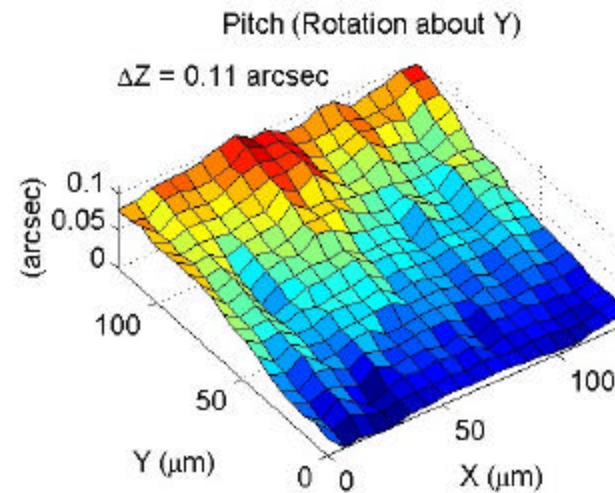
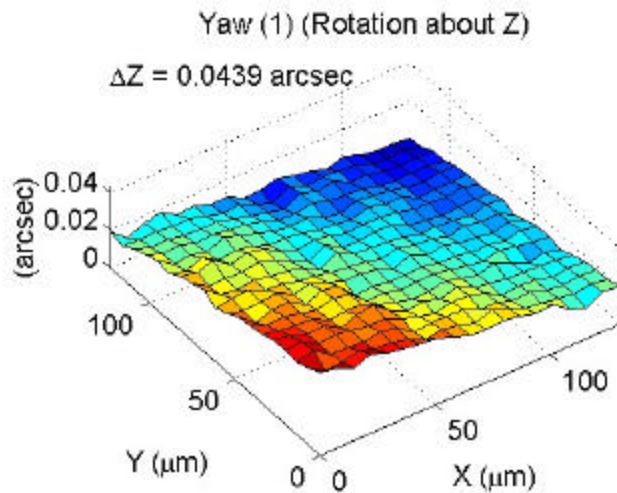
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## Experimental Set-up for Rotational Error Testing





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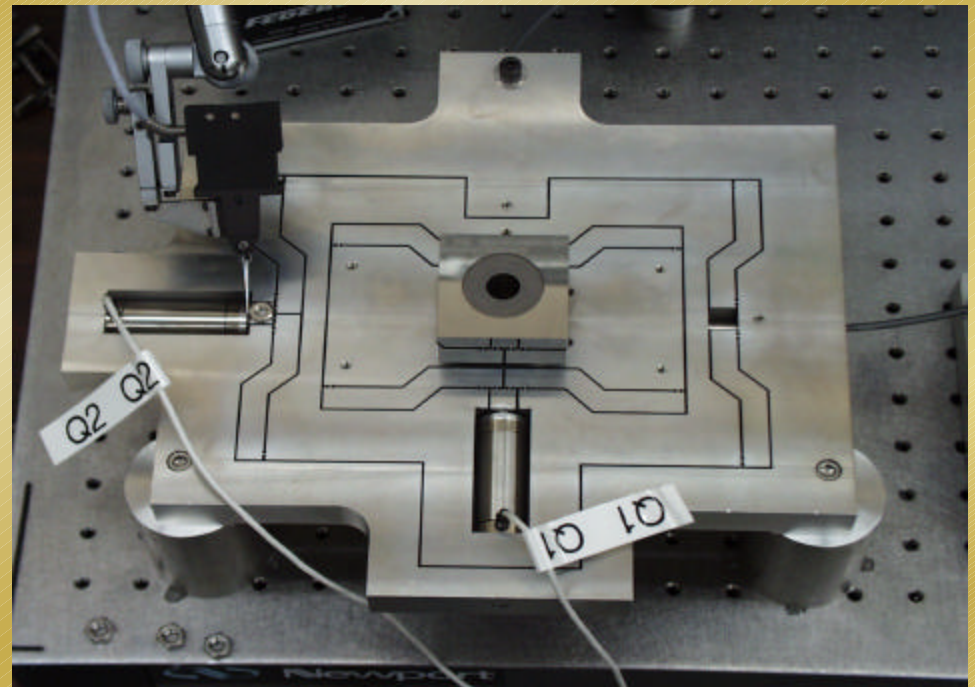


Range of Stage is 130 X 130 micrometers

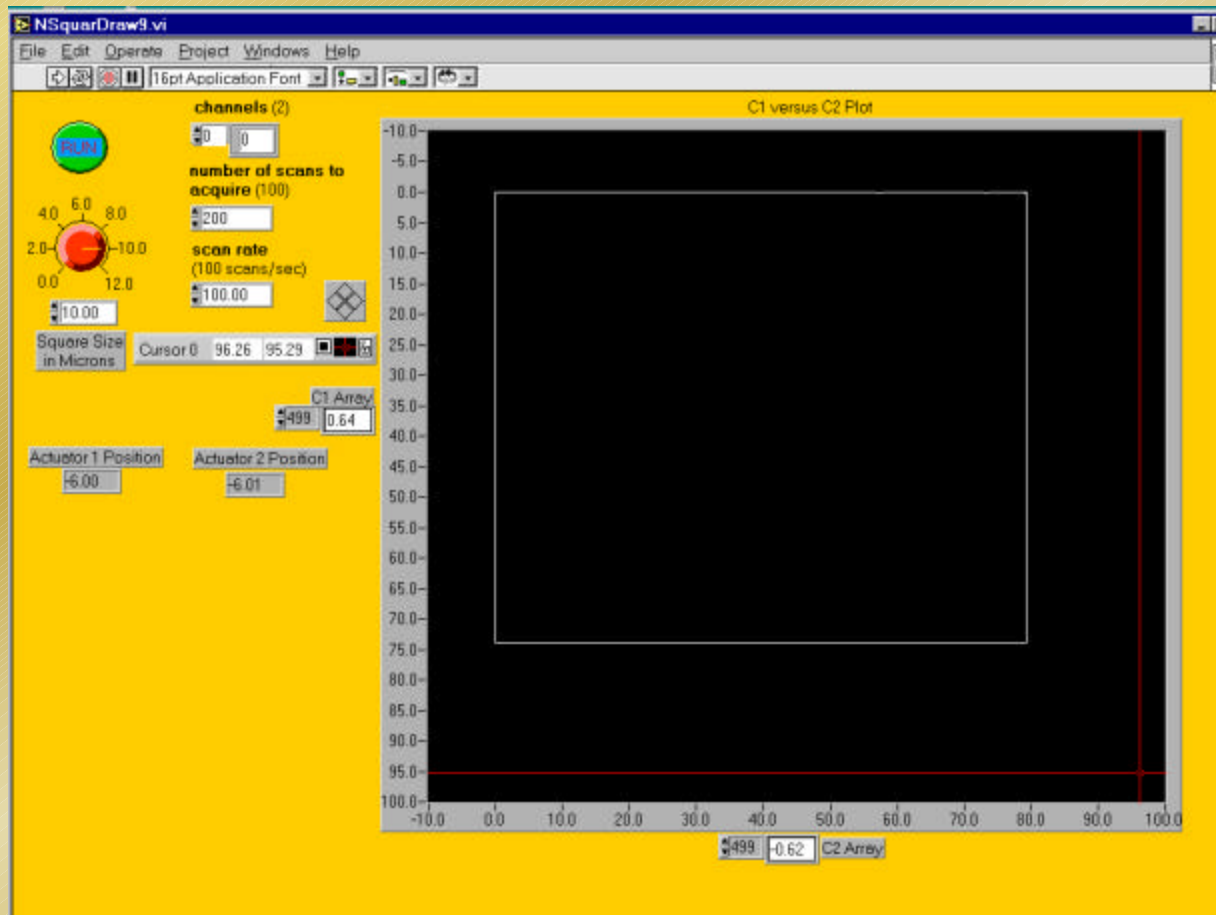
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# Axis Crosstalk

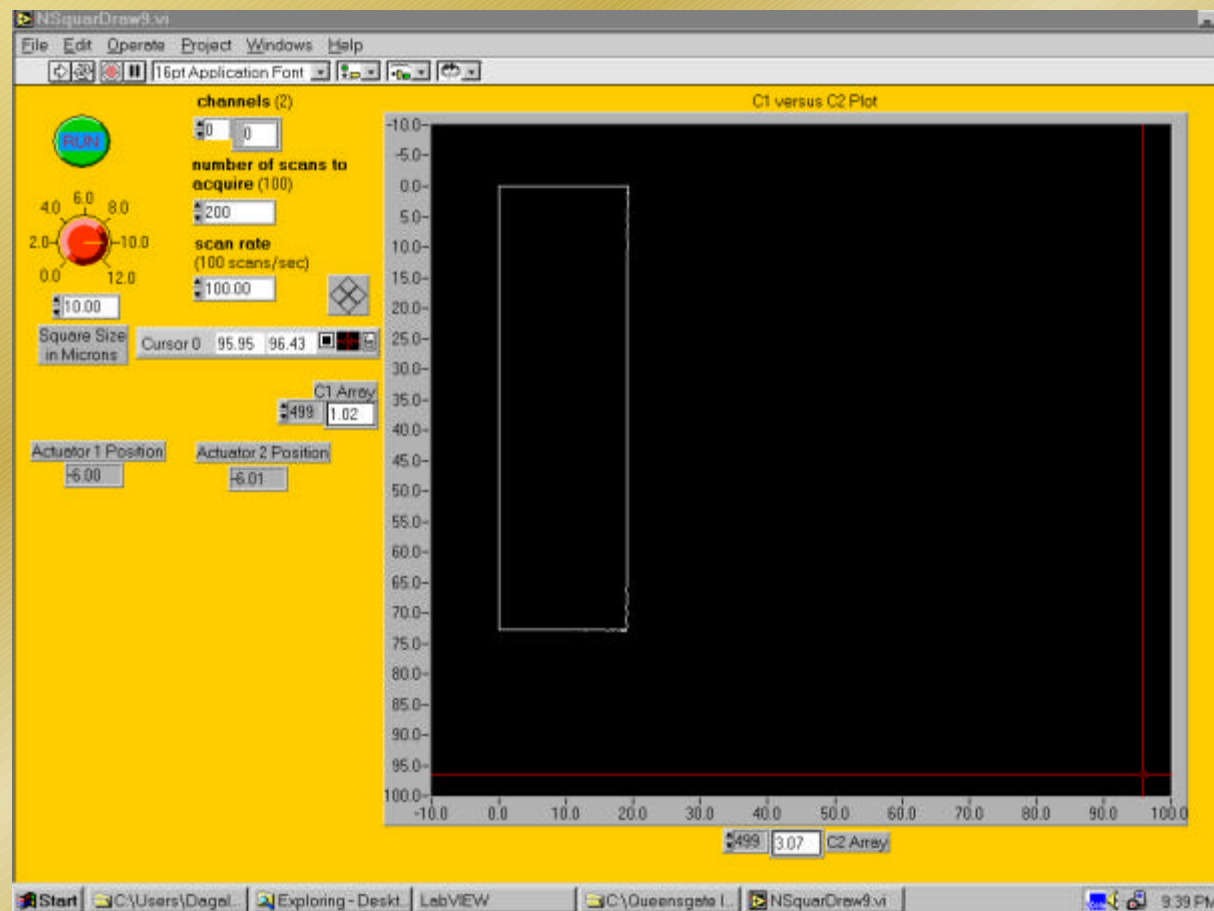
- Static checks indicate crosstalk to be approximately one part in 4000 (25 nm over 100 micrometers) -- on old stage design.



# Baseline Control Trajectory

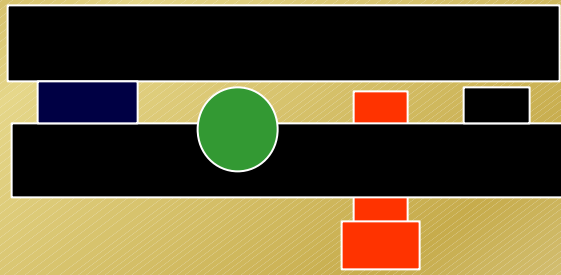


## Defective Coupling Control Trajectory

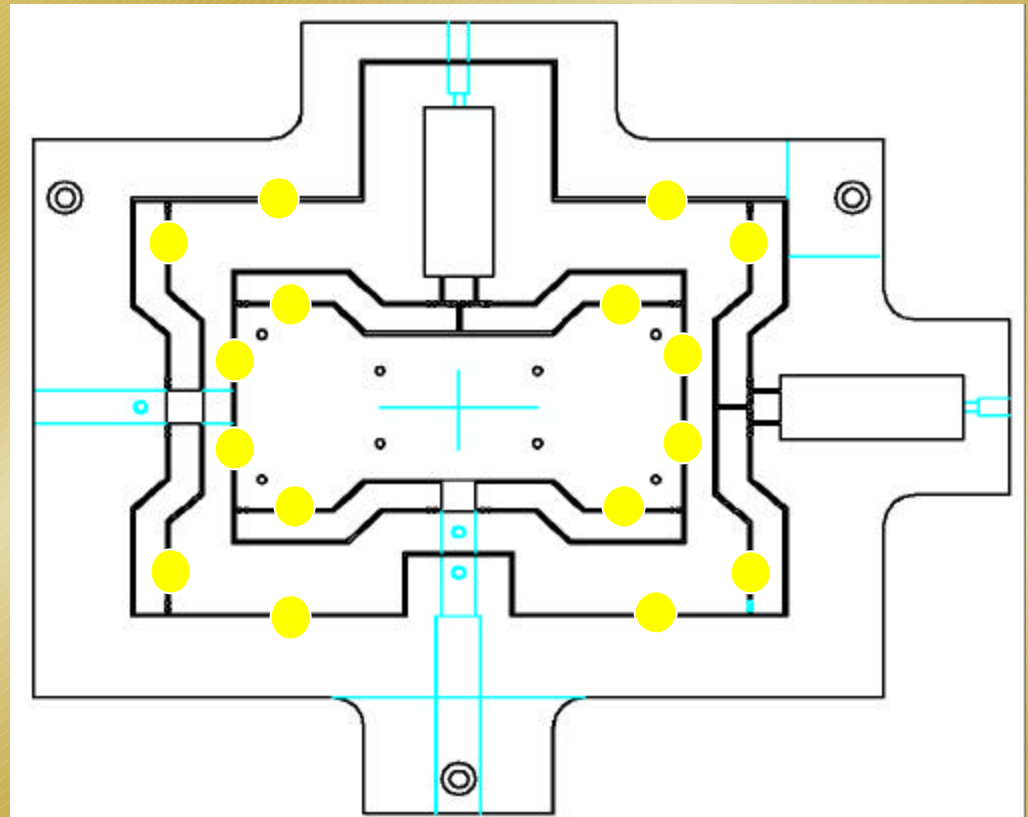


Future Work  
including 3-D Space  
Micro-Positioner Designs

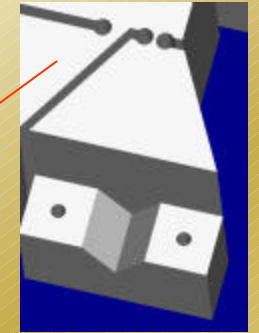
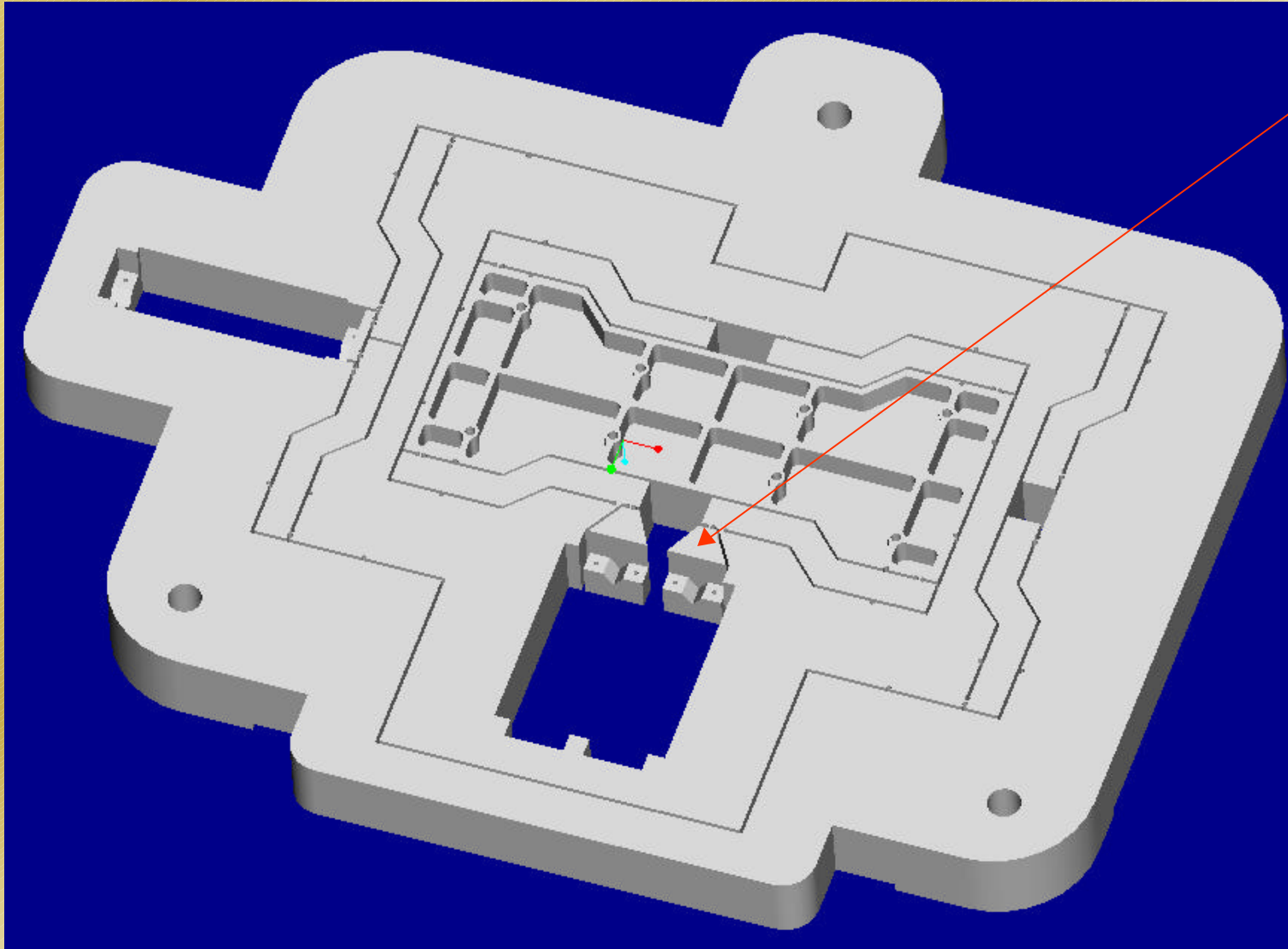
## Safety Stops



- Elastomer
- Plastic or Steel Rod
- Stop Screw
- Designed/Machined Stop

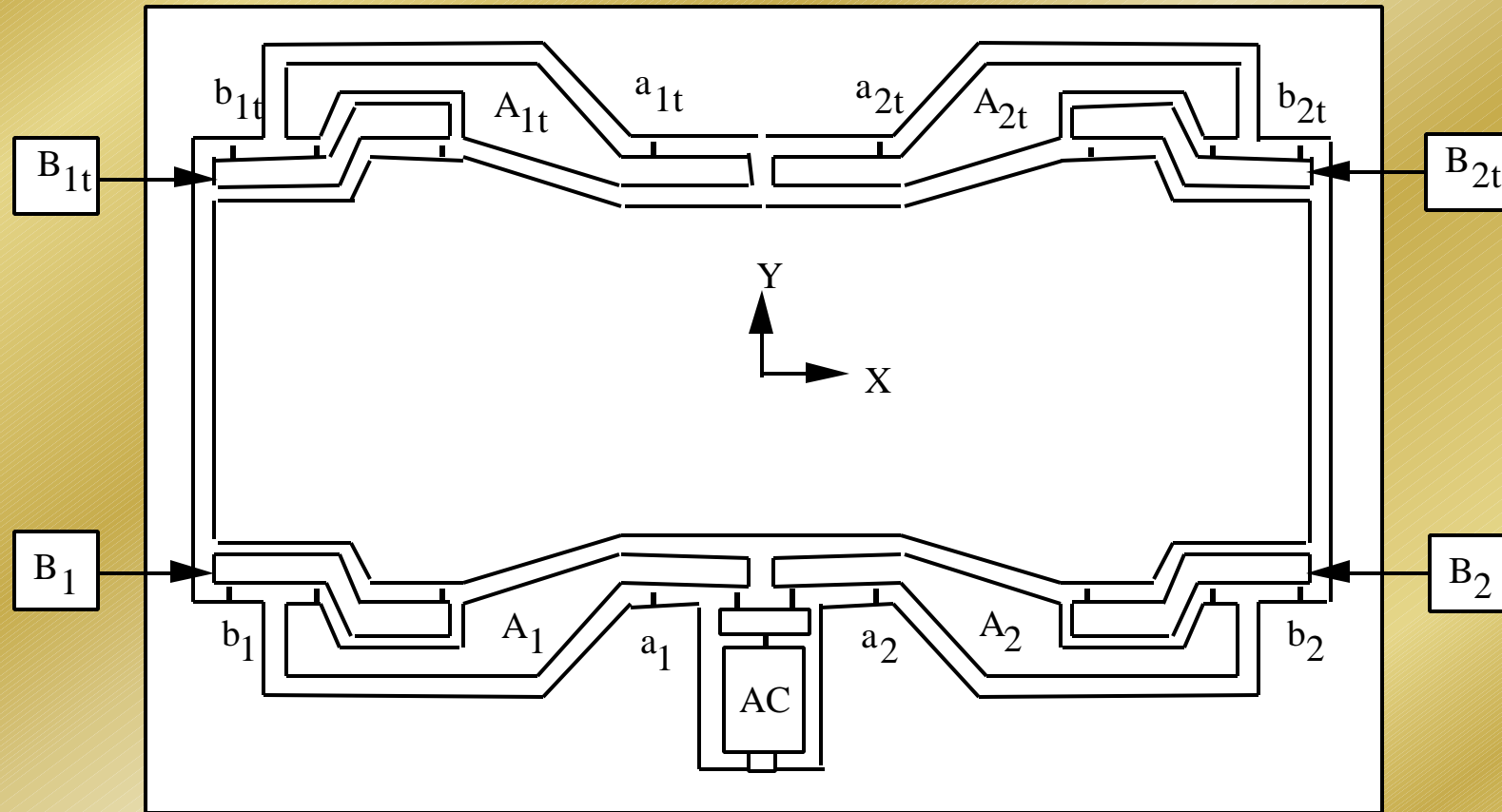


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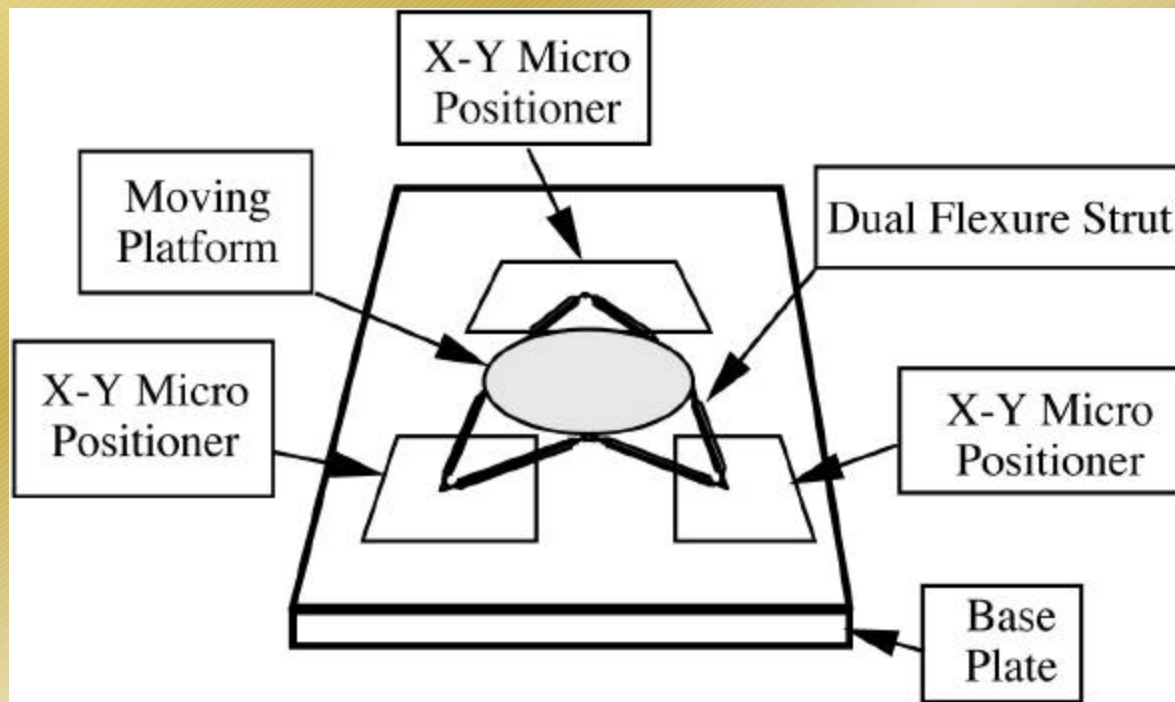
# Reduce Size with Compound Cantilevers



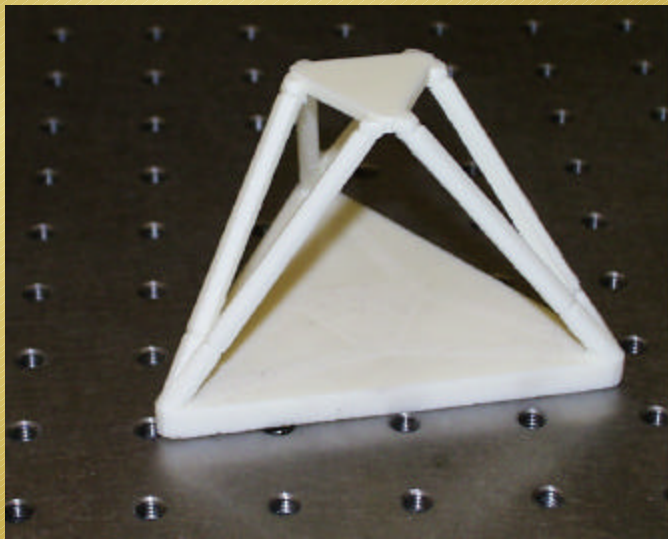
Only shows Y-axis



## 6-Degree of Freedom Tri Stage Micro-positioner

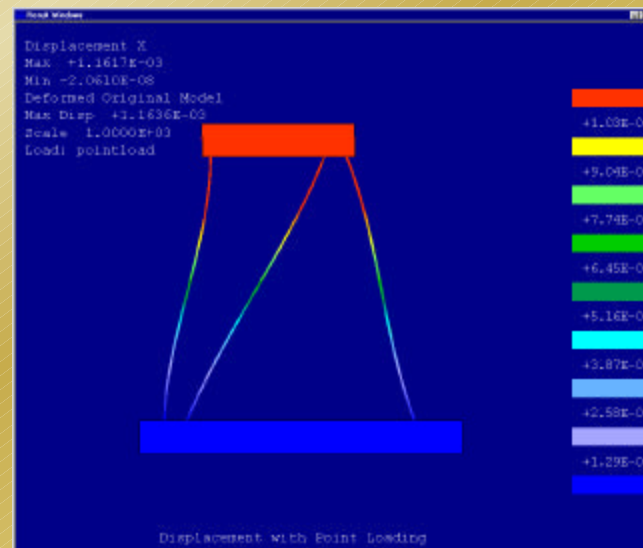
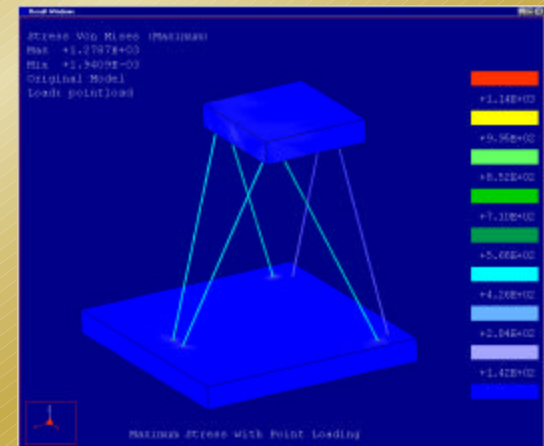


## MicroDevices - Performance Measures

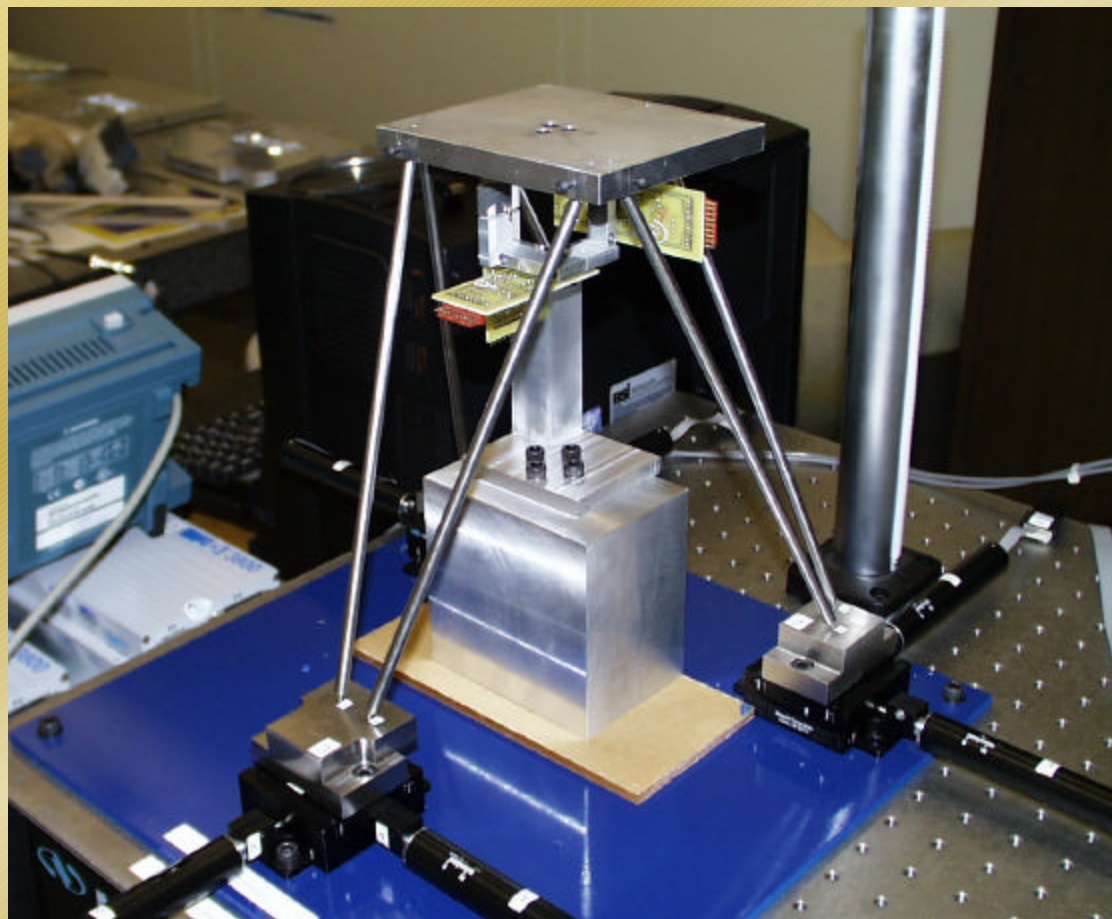


6 Degree of Freedom  
Microstage Prototype

Advanced  
Performance  
Measures and  
Design Tools



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### Planar Stage Performance (unqualified)

- Angular Crosstalk Error

0.04 to 0.2 arcseconds

- Translational Crosstalk Error

1 part in 4000, 25nm over 100 micrometers

- Stage Range

130 X 130 micrometers

- PZT/Coupler/Stage Transmission Ratio

70 - 75 %

- Cantilever Gain 10 to 1

- Closed-Loop Resonant Frequency ~ 66 Hz on the new stage

- Material of Prototypes Aluminum 6061-T6



## Summary (continued)

- Accuracy, Repeatability, Straightness
  - ( ISO 230-2, ASME B5.54)
- Stage issues to be resolved - constraints, dynamics
- X-Y Micro-positioners performance measures and testing software
- Beginning to apply performance measures and testing to 6DOF micro-positioners

## For more information:

- Information posted on our website:
  - Final Report on Micro-Meso Scale Manufacturing Exploratory Project and Workshop proceedings:
    - Manufacturing Technology for Integrated Nano- to Millimeter (In2m) Sized Systems, March 1999
    - Manufacturing Three-Dimensional Components and Devices at the Meso and Micro Scales, May 1999
  - Copy of these vu-graphs

[http://www.isd.mel.nist.gov/meso\\_micro/](http://www.isd.mel.nist.gov/meso_micro/)

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